

Supplementary Materials: A Multi-Position Drum-Type Assembly for Simultaneous Film Deposition at Different Temperatures in a Single Sputter Cycle—Application to ITO Thin Films

Akhmed K. Akhmedov ¹, Abil Sh. Asvarov ^{1,2,*}, Arsen E. Muslimov ² and Vladimir M. Kanevsky ²

¹ Institute of Physics, Dagestan Research Center of Russian Academy Sciences, Yaragskogo str., 94, Makhachkala 367015, Russia; cht-if-ran@mail.ru

² Shubnikov Institute of Crystallography, Federal Scientific Research Center “Crystallography and Photonics” of Russian Academy of Sciences, Leninsky prospect, 59, Moscow 119333, Russia; amuslimov@mail.ru (A.E.M.); kanev@crys.ras.ru (V.M.K.)

* Correspondence: abil-as@list.ru

Figure S1 shows some specific details regarding the design of the separate heated substrate holder (in particular, it can be seen how the U-shaped spiral heater is electrically isolated from the holder’s stainless steel body by quartz tubes, as well as the system of thermal shields on it and the clamping mechanism for holding the substrates).

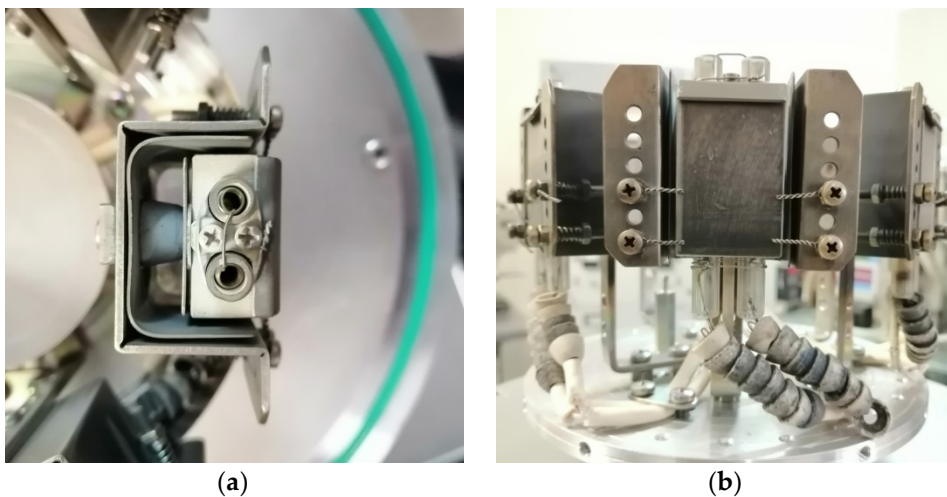


Figure S1. Photos of one of the heated holders of the MPDTA seen from different angles.

Figure S2 shows additional information about the construction of the vacuum electrical feedthrough (part 7 in Figure 1 of the main text).

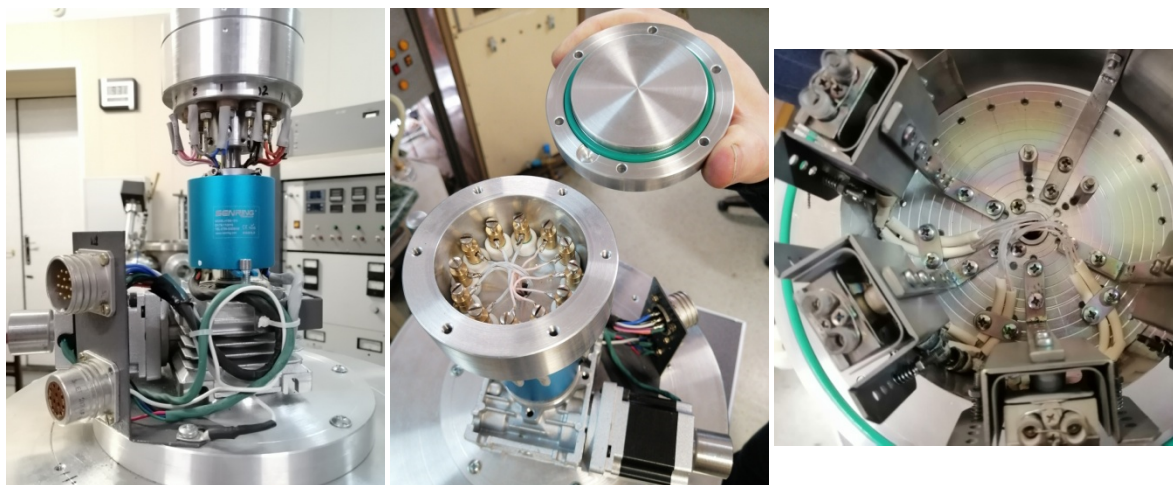


Figure S2. Additional information about the vacuum electrical connector.

Publisher's Note: MDPI stays neutral with regard to jurisdictional claims in published maps and institutional affiliations.



© 2020 by the authors. Submitted for possible open access publication under the terms and conditions of the Creative Commons Attribution (CC BY) license (<http://creativecommons.org/licenses/by/4.0/>).